NIKON CF OBJECTIVES 210mm TUBE LENGTH

for Industrial Applications



- REFLECTED LIGHT BRIGHTFIELD
- REFLECTED BRIGHT/DARKFIELD
- REFLECTED POLARIZED LIGHT AND NOMARSKI TECHNIQUES
- PETROGRAPHIC APPLICATIONS
- INTERFEROMETRY

CF® BRIGHTFIELD REFLECTED LIGHT OBJECTIVES

CF M Plan Achromats and CF M Plan Apochromats provide exceptional clarity, contrast and flatness when used in viewing metallurgical, electronic, and other opaque specimens. They are flatfield from edge to edge, permitting ultra-wide observation with identical sharpness from center to edge. The complete line of reflected light objectives includes the ELWD and SLWD series which are invaluable for inspecting IC's in packages. For critical examination of specimens, use the high-resolution CF M Plan Apochromats.



Objective Type	Magnification	Product Number	Numerical Aperture	Working Distance mm	Focal Length mm	Price
CF M 1	² 1X	78777	0.03	10.2	207.20	\$2,794.00
Plan	² 1.5X	78762	0.045	3.6	125.8	3,029.00
Achromat	² 2.5X	78760	0.075	11.0	76.68	1,079.00
	5X	78731	0.10	20.0	37.64	524.00
	10X	78732	0.25	9.0	21.19	692.00
	20X	78733	0.40	2.7	10.0	752.00
	40X	78734	0.65	1.0	5.26	868.00
	60X	78735	0.80	0.30	3.72	1,118.00
	100X	78737	0.90	0.30	2.13	1,485.00
	LWD 20X	78729	0.40	6.0	10.1	1.108.00
	LWD 40X	78730	0.55	3.0	5.19	1,385.00
	LWD 100X	79235	0.90	1.00	2.04	2,892.00
	ELWD 20X	78775	0.40	10.5	11.1	1,145.00
	ELWD 40X	78776	0.50	10.1	5.1	1,277.00
	ELWD 60X	79233	0.70	4.90	3.49	2,292.00
	ELWD 100X	79237	0.80	2.0	2.04	4,329.00
	SLWD 10X	79295	0.21	20.4	20.56	1,149.00
	SLWD 20X	79296	0.35	19.9	9.94	1,637.00
	SLWD 40X	79297	0.40	14.9	5.10	2,124.00
	SLWD 100x	79299	0.75	4.7	2.01	4,223.00
	100X Oil	78736	1.25	0.23	2.23	1,868.00
CF M Plan Achromat	50X PC w/corr	79248	0.7	2.9	4.34	6,199.00
Suitable for	100X PC w/corr	79249	0.8	1.0	2.07	6,199.00
surface inspection	50X PMMA w/corr	79288	0.7	2.6	4.31	6,199.00
of optical disks	100X PMMA w/corr	79289	0.8	1.0	2.06	6,199.00
CF M	40X	78860	0.80	0.70	5.2	2,073.00
Plan	50X	78738	0.90	0.22	4.24	2,880.00
Apochromat	100X	79242	0.95	0.32	2.0	3,625.00
•	150X	79243	0.95	0.20	1.4	3,334.00
	200X	79244	0.95	0.20	1.4	3,855.00

¹78777 1X objective must be used in conjunction with 79503 polarizer and 79504 analyzer in order to achieve anti-glare reflex performance built into this objective. The objective has a dovetail mount, no nosepiece required.

²Will vignette with 10x UW eyepieces.

CF BRIGHT/DARKFIELD OBJECTIVES FOR REFLECTED LIGHT

The BD Plan Achromats and BD Plan Apochromats furnish the best of brightfield and darkfield methods in one. Darkfield is a popular method for locating scratches or inclusions on the surface of opaque specimens. Designed for use on the B/D Nosepiece, light from the specimen travels through the objective barrel, thus providing excellent contrast in darkfield. All objectives are dry, and, thus, easy to handle because there is no need for immersion oil.



Objective Type	Magnification	Product Number	Numerical Aperture	Working Distance mm	Focal Length mm	Price
CF BD	5X	78740	0.10	9.0	37.64	\$ 638.00
Bright/	10X	78741	0.25	3.0	21.19	823.00
Darkfield	20X	78742	0.40	2.5	10.0	923.00
Plan	40X	78743	0.65	1.0	5.26	1,048.00
Achromat	50X	78763	0.85	0.56	4.12	1,387.00
	60X	78753	0.80	0.35	3.72	1,288.00
	100X	78754	0.90	0.39	3.49	2,023.00
	ELWD 20X	78861	0.4	8.50	11.60	1,230.00
	ELWD 40X	78862	0.5	9.80	5.26	1,578.00
	ELWD 60X	79234	0.70	4.90	3.49	2,441.00
	LWD 100X	79236	0.90	1.00	2.04	3,021.00
	ELWD 100X	79238	0.80	2.0	2.04	4,605.00
CF BD	40X	79290	0.8	0.7	5.2	2,989.00
Bright/	100X	79292	0.9	0.43	2.0	3,945.00
Darkfield	150X	79293	0.9	0.3	1.4	3,898.00
Plan Apochromat	200X	79294	0.9	0.3	1.03	4,475.00

CF BD/DIC M PLAN ACHROMATS

CF BD/DIC M Plan Achromats are the most versatile metallurgical objectives available. They are designed to perform brightfield, darkfield, polarized light & Nomarski techniques, thus eliminating the need for separate objectives for each technique. The CF BD/DIC M Plan Achromats are dry, eliminating the need for oil.



Objective Type	Magnification	Product Number	Numerical Aperture	Working Distance mm	Focal Length mm	Price
CF BD/DIC	5X	78870	0.10	9.0	37.64	\$ 685.00
M Plan	10X	78871	0.25	3.0	21.19	908.00
Achromat	20X	78872	0.40	2.5	10.0	1.036.00
	40X	78873	0.65	1.0	5.26	1.198.00
	50X	78764	0.85	0.56	4.12	1,555.00
	100X	78874	0.90	0.39	2.13	2,197.00

CF M PLAN DIC OBJECTIVES FOR REFLECTED LIGHT

CF M Plan DIC objectives are designed for reflected Normarski DIC system and standard polarized light. These strain free objectives help minimize the depolarization effects. They also offer a remarkably high EF (extinction factor). The reflected Normarski DIC system is used to gain surface relief that is not attainable with brightfield. Since all DIC objectives are dry type, immersion oil is not necessary.



Objective Type	Magnification	Product Number	Numerical Aperture	Working Distance mm	Focal Length mm	Price
CF DIC	5X	78852	0.10	20.0	27.6	\$ 575.00
M Plan	10X	78853	0.25	9.0	21.2	830.00
Achromat	20X	78854	0.40	2.7	10.0	922.00
	40X	78855	0.65	1.0	5.3	1,152.00
	100X	78856	0.90	0.3	2.1	2,208.00

Note: When using any M-Plan objective in a BD or Universal Nosepiece, the 78797 objective adapter must be used.

CF M FLUOR AND CF PM FLUOR OBJECTIVES FOR REFLECTED LIGHT

Characteristic of the M Fluor Achromat series of objectives are the extremely high transmission capabilities for all wavelengths, i.e. 60% in the 340mm range and ultra high numerical apertures signifying increased resolving power. These two features allow these objectives to be used reliably for lithography applications. Their high light gathering ability also allows these lenses to perform beautifully during low level fluorescence.

The most common application for the PM Fluor 20X and 40X oil immersion objectives are in the Coal/Oil Industry. Petroleum geologists use them for vitrinite testing with a reflected light microscope photometer system. They are excellent for all polarized reflected light applications, especially for conoscopy of low reflectance specimens.



Objective Type	Magnification	Product Number	Numerical Aperture	Working Distance mm	Focal Length mm	Price
CF M Fluor Achromat*	14X 26X 50X	79305 79306 79307	0.50 0.75 0.85	0.64 0.66 0.45	14.3 7.8 4.16	\$1,475.00 1,677.00 2,054.00
CF PM Fluor Achromat	20X 40X	78770 78771	0.60 1.00	0.40 0.41	10.7 5.5	1,598.00 2.007.00

^{*79308} UV Cut Slider is recommended for use with CF M Fluor objectives. The price is \$29.00

NOMARSKI PRISMS FOR DIFFERENTIAL INTERFERENCE CONTRAST

Prism Part Number	Nomarski Prism	Price	Objective	
79537	5x	\$ 529.00	For 5X #78852, 78870	_
79538	10/100x	529.00	For 10X #78853, 78871, 100X #78856, 78874	
79539	20x	529.00	For 20X #78854, 78872	
79540	40x	529.00	For 40X #78855, 78873	
79568	50x	529.00	For 50X #78764	
79541	A/1	683.00	For 100X #79235, 79237, 79242, 79236, 79238, 79292 200X #79294	
79542	B/2	683.00	For 40X #78730, 78862	
79543	C/3	683.00	For 40X #78860, 79290 60X #79234	
79544	D/4	683.00	For 20X #78861 60X #78735, 78753	
79545	E/5	683.00	For 150X #79243, 79293	

CF DI AND CF MI INTEROMETRY OBJECTIVES FOR REFLECTED LIGHT

CF Interference objectives are used in determining height differences of reflected light specimens.

DI double beam (Mirau) and TI (Michaelson) objectives make no contact with the specimen. Measuring accuracy is 1/10 of the wavelength used (approximately 50-60nm with 550 GIF filter). The new TI series 2.5 and 5x allow low power interferometry over larger areas and have a built-in 2° tilting mirror.

The MI multiple beam (Tolansky) objectives provide higher measuring accuracy, down to 1/100 of the wavelength (approximately 5nm with 540 IF Narrow band filter), due to their sharper fringes. They utilize a reference mirror which must be brought into direct contact with the specimen.



Objective Type	Magnification	Product Number	Numerical Aperture	Working Distance mm	Focal Length mm	Price
CF DI & TI	DI 10X	79100	0.25	4.0	21.3	\$ 908.00
Non Contact Interferometry		79101	0.40	1.9	10.1	1,118.00
	DI 40X	79138	0.50	3.9	5.1	2,153.00
	TI 2.5X*	79283	0.075	11.1	77.8	4,423.00
	TI 5X*	79284	0.1	9.0	37.7	2,298.00
CF MI	MI 10X	79102	0.25		21.3	809.00
Contact	MI 20X	79103	0.40		10.1	953.00
Interferometry	MI 40X	79139	0.50		5.1	2,001.00
Reference	79104	4% ref. mirro	r for 10X & 20X MI	objectives		105.00
Mirrors	79105	40% ref. mirr	or for 10X & 20X MI	objectives		105.00
for MI objectives	79106	65% ref. mirr	or for 10X & 20X MI	objectives		105.00
,	79107		or for 10X & 20X MI			105.00
	79143	4% ref. mirro	r for 40X MI objective	ves		131.00
	79140	40% ref. mirr	or for 40X MI object	tives		123.00
	79141	65% ref. mirr	or for 40X MI object	tives		123.00
	79142	90% ref. mirr	or for 40X MI object	tives		123.00
	79109	Ref. mirror he	older for MI objective	res		144.00

^{*}These objectives have a dovetail mount, no nosepiece required.

NOTES:

- Use 79083 IF narrow band green (540nm) filter for MI objectives.
- Use 79082 GIF green filter for DI and TI objectives.
- TI objectives are not parfocal with other CF objectives.
 Parfocal distance TI 2.5x = 7.94mm (not useable on IC-66)
 TI 5x = 48.6mm
- TI objectives supplied with single objective adapter or can be mounted on 79025 BD nosepiece.
- Use 79108 CFS 10x eyepiece (FN 12) with MI and DI to restrict field of view to area with fringes.

EYEPIECES

CF High eyepoint widefield eyepieces are the standard, designed to be used with all objectives. For a super widefield of view, there are the CF high eyepoint ultra-widefield eyepieces which are designed to be used with a special ultra-wide head.

In addition, a filar micrometer eyepiece is available which offers easy calibration and extremely accurate readings down to 0.01mm. The filar may be used with CF objectives from 2.5X to 100X.



CF Eyepiece Type	Magnification	Product Number	Field Number mm	Focal Length mm	Price
CF-E High-Eyepoint Widefield*	CF-E 5X CFW-E 10X CFW-E 15X	78415 78416 78417	18.6 18.0 16.7	40.0 25.0 16.7	\$ 76.00 52.00 76.00
CF High Eyepoint Widefield	CFWN 8X CFWN 10X CFWN 10X PM CFWN 10X CM CFWN 10X CR CFS 10X CFWN 12.5X CFWN 15X	84225 84220 84221 84268 84228 79108 84226 84227	20.0 20.0 20.0 18.0 18.0 12.0 16.0	31.3 25.0 25.0 25.0 25.0 25.0 20.0 16.7	266.00 172.00 271.00 308.00 366.00 141.00 426.00 182.00
CF High Eyepoint Ultra Widefield	CFUWN 10X CFUWL 10X CFUWN 10X PM CFUWN 15X	84222 81530 84223 84249	26.5 25.0 26.5 17.5	25.0 25.0 25.0	468.00 548.00 641.00 1,054.00

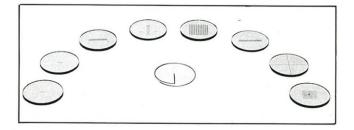
^{*}For BJ and FJ Body Tubes only.

RETICLES

To accommodate your needs, Nikon offers a full range of reticles for quantitative and qualitative measurement.

RETICLES 21.0mm

Fits built-in reticle holder of most CFWN eyepieces.



Description	Product #	Price	
.1 inch scale in 100 graduations	SO75950	\$ 58.00	
.5 inch scale in 100 graduations	SO75955	58.00	
5mm scale in 100 graduations	SO75960	58.00	
10mm scale in 100 graduations	SO75961	58.00	
1mm squares	SO75962	58.00	
5mm squares	SO75963	58.00	
Crossline 90°	SO75966	58.00	
Whipple Disc	SO75967	58.00	
Eyepiece Pointer	76960	5.00	

STAGE MICROMETER

Extremely accurate calibration is afforded with a choice of three stage micrometers.



Description	Product #	Price	
Stage Micrometer A 1mm scale divided into 100 parts	76954		\$106.00
Stage Micrometer B .2mm scale with 400 squares	76955		106.00
Stage Micrometer for reflected light .04 inch in 40 parts (0.001 inch)			
Manufactured with equipment traceable to N.I.S.T. standards	75626		265.00

\$162.00	
Φ102.00	
4.00	
5.00	
5.00 29.00	
3.00	
50.00	
	5.00 29.00 3.00 3.00



50X and 100X PMMA CF M Plan Objectives

To find depth of focus, use this formula:

Depth of Focus = $\frac{n \times \lambda}{2 \times (N.A.)^2} + \frac{n}{7 \times N.A. \times M}$

To find resolving power, use this formula:

Resolving power = $\frac{\lambda}{2 \times N.A}$

Where n = Refractive index

Where $\lambda = 0.55 \,\mu\text{m}$ standard wavelength

DESIGNATIONS ON OBJECTIVES AND EYEPIECES

LWD - Long working distance

ELWD - Extra long working distance

SLWD - Super long working distance

w/corr - With correction collar for coverslip or coating thickness

M - Metallurgical objectives (210mm)

DI - Interferometry; double beam, Mirau

TI - Interferometry; multiple beam, Michaelson

MI - Interferometry; multiple beam, Tolansky

DIC - Differential Interference Contrast

PM - For polarized light; reflected

PLAN - Flat field

Fluor - High UV transmission

PC - Objective used for viewing specimen with polycarbonate surface film layer

PMMA - Objective used for viewing specimen with polymethyl methacrylate surface film layer

CFWN - High eyepoint widefield eyepiece

CFUWN - High eyepoint ultra widefield eyepiece

PM - Eyepiece designation-photomask reticle

CM - Eyepiece designation-crossline reticle for polarizing microscope

 CR - Eyepiece designation-concentric circles for photometer

CFS - Eyepiece designation for use with MI and DI objectives

When cleaning objectives and eyepieces use fresh, anhydrous xylene and lens paper.

All prices are suggested selling prices.

Price and specifications subject to change without notice.



Regional Offices:

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